

Application/Control Number: 10/036,629

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Art Unit: 2800

CLMPTO

AJ

08/10/04

Cancelled claims 1-5

6. A method for sensing pressure, comprising the steps of:

directing a beam of light through a junction in a semiconductor substrate and onto a beam;

providing an optical resonant cavity between said junction and said beam to impose a

frequency on said beam of light;

vibrating said beam by electrostatic attraction between said junction and said beam;

varying a frequency of vibration by said beam by changes in pressure to effect changes in said

beam of light; and

sensing said changes in said beam of light.

7. A method as claimed in claim 6, further comprising the step of:

providing a evacuated chamber within which said beam is mounted, said evacuated chamber

having an outer shell defining an optical resonant cavity between said outer shell and

said beam.

Cancelled claim 8